



## IEEE EDS Kansai Chapter of the Year Award

**Yoshihiro Sato**  
(Panasonic Corporation)



"Characterization Scheme for Plasma-Induced Defect Creation  
due to Stochastic Lateral Straggling in Si Substrates  
for Ultra-low Leakage Devices"  
[IEEE IEDM]



## IEEE EDS Kansai Chapter MFSK Award

**Kazuki Monta**  
(Kobe University)



"Secure 3D CMOS Chip Stacks with Backside Buried  
Metal Power Delivery Networks for Distributed  
Decoupling Capacitance"